## **IN THE CLAIMS**

Please amend claims 9 through 11, and add claims 12 through 14 as follows:

1. (Previously Amended) A magnesium titanate implant, comprising:

an implant body containing titanium or a titanium alloy; and

a magnesium titanate oxide film formed on the surface of the said implant body in a single or mixed solution containing magnesium by low voltage dielectric breakdown anodic oxidation.

## Claim 2. (Canceled)

- 3. (Previously Amended) The magnesium titanate implant as set forth in claim 1, wherein the magnesium titanate oxide film contains 6 to 26% of titanium, 51 to 71% of oxygen and 1.8 to 32% of magnesium, as main ingredients.
- 4. (Previously Amended) The magnesium titanate implant as set forth in claim 1, wherein the magnesium titanate oxide film has a bilayer structure including an upper porous layer and a lower barrier layer.
- 5. (Previously Amended) The magnesium titanate implant as set forth in claim 1, wherein the magnesium titanate oxide film has a thickness of 300 nm to 30 μm.

- 6. (Original) The magnesium titanate implant as set forth in claim 5, wherein the magnesium titanate oxide film has a thickness of 500 nm to  $10 \mu m$ .
- 7. (Original) A process for preparing a magnesium titanate oxide film implant, comprising:

irradiating UV light on an implant body made of titanium or a titanium alloy in distilled water for more than 2 hours;

dipping the UV light-irradiated implant body in an electrolyte solution containing magnesium; and

coating a magnesium titanate oxide film on the dipped implant body by anodic oxidation at a voltage of 60 to 500V.

- 8. (Original) The process as set forth in claim 7, wherein the electrolyte solution is a single or mixed solution containing magnesium.
- 9. (Currently Amended) The process as set forth in claim 7 or 8, wherein the electrolyte solution has a concentration ranging from 0.01M to 1.0M.
- 10. (Currently Amended) The process as set forth in claim 7 or 8, wherein the electrolyte solution has a pH of 3.0 to 12.5.

- 11. (Currently Amended) The process as set forth in claim 7 or 8, wherein the current density for performing the anodic oxidation is within the range of 30 to 4000 mA/cm2.
- 12. (New) The process as set forth in claim 8, wherein the electrolyte solution has a concentration ranging from 0.01M to 1.0M.
- 13. (New) The process as set forth in claim 8, wherein the electrolyte solution has a pH of 3.0 to 12.5.
- 14. (New) The process as set forth in claim 8, wherein the current density for performing the anodic oxidation is within the range of 30 to 4000 mA/cm2.